

Notice of References Cited

Application/Control No.

10/797,231

Applicant(s)/Patent Under
Reexamination
HAMMOND ET AL.

Examiner

Alexander G. Ghyka

Art Unit

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

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Alex Ghyka 11/12/06